

Applic. No. 10/609,464

Amdt. dated April 30, 2005

Reply to Office action of February 7, 2005

Claim Amendments

This listing of the claims will replace all prior versions, and listings, of claims in the application:

Claim 1 (currently amended): A method for characterizing and simulating a chemical mechanical polishing (CMP) process for a substrate to be polished by a polishing cloth and rotated relative to the polishing cloth for a defined polishing time, which comprises the method steps of:

defining a set of process parameters;

preparing and characterizing a test substrate having test patterns with different structure densities using the process parameters defined;

determining a set of model parameters for simulating the CMP process from results of the characterizing of the test substrate;

determining layout parameters of the substrate to be polished;

defining a profile of demands for a CMP process result for the substrate to be polished; and

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simulating the CMP process for determining the defined
polishing time required for satisfying the profile of demands;
and

outputting the defined polishing time for use in a polishing
process.

Claim 2 (original): The simulation method according to claim
1, which further comprises during the preparing and
characterizing step, characterizing the test substrate in an
experimental polishing time grading sequence.

Claim 3 (original): The simulation method according to claim
1, which further comprises forming the set of model parameters
to include an abrasion rate, a hardness of the polishing
cloth, and a characteristic filter length for determining
effective structure densities.

Claim 4 (original): The simulation method according to claim
3, which further comprises determining the abrasion rate and
the hardness from a layer thickness development of a test
pattern with a mean structure density of the test substrate.

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Claim 5 (original): The simulation method according to claim 3, which further comprises determining the filter length from a global step height of all the test patterns of the test substrate.

Claim 6 (original): The simulation method according to claim 3, which further comprises forming the layout parameters of the substrate to include a minimum and maximum effective structure density determined over the filter length and a starting step height.

Claim 7 (original): The simulation method according to claim 1, which further comprises defining the profile of demands from a global step height to be achieved on the substrate after the CMP process has been carried out.

Claim 8 (original): The simulation method according to claim 7, which further comprises determining a deposition thickness required to carry out the CMP process during the simulating step.

Claim 9 (original): The simulation method according to claim 8, which further comprises determining a minimum achievable global step height during the simulating step.

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Claim 10 (original): The simulation method according to claim 9, which further comprises selecting the global step height to be achieved in dependence on the minimum achievable global step height.

Claim 11 (original): The simulation method according to claim 6, which comprises performing the following steps during the step of determining the layout parameters:

determining a surface coverage of structures for at least one region on the substrate;

determining a cross-sectional profile of the structures;

calculating a local structure density from the surface coverage and the cross-sectional profile of the structures;
and

calculating an effective structure density from the local structure density by forming a mean over the filter length.

Claim 12 (original): The simulation method according to claim 11, wherein the cross-sectional profile is dependent on a type of process which can act on the substrate and the structures.

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Claim 13 (original): The simulation method according to claim 12, wherein the cross-sectional profile is dependent on a structure size.

Claim 14 (original): The simulation method according to claim 13, which further comprises selecting the type of process from the group consisting of a deposition process and an etching process, and the cross-sectional profile has at least one edge with an angle of inclination with respect to a surface of the substrate which is not 90 degrees.

Claim 15 (original): The simulation method according to claim 14, which further comprises calculating a first volume by integration of the cross-sectional profile over a basic area of a structure for performing the step of calculating the local structure density.

Claim 16 (original): The simulation method according to claim 15, which further comprises dividing the first volume by a second volume calculated from a product of the basic area of the structure and the starting step height.

Claim 17 (original): The simulation method according to claim 1, which further comprises defining the set of process parameters to include a compressive force and a relative

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rotational speed between the substrate and the polishing cloth.

Claim 18 (original): The simulation method according to claim 1, which further comprises using a semiconductor wafer as the substrate.

Claim 19 (original): A method for chemically mechanically polishing a substrate, which comprises the steps of:

performing a method for characterizing and simulating the chemical mechanical polishing (CMP) process, by the steps of:

defining a set of process parameters;

preparing and characterizing a test substrate having test patterns with different structure densities using the process parameters defined;

determining a set of model parameters for simulating the CMP process from results of the characterizing of the test substrate;

determining layout parameters of the substrate to be polished;

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defining a profile of demands for a CMP process result
for the substrate to be polished; and

simulating the CMP process for determining a polishing
time required for satisfying the profile of demands;

depositing a layer to be planarized on the substrate; and

polishing the substrate for a duration of the polishing time
determined from the simulating step.

Claim 20 (original): The polishing method according to claim
19, which further comprises:

determining a deposition thickness required to carry out the
CMP process during the simulating step; and

depositing the layer to be planarized to the deposition
thickness required.

Claim 21 (original): The simulation method according to claim
19, which further comprises using a semiconductor wafer as the
substrate.